

IFW

1 6. (original) The method of claim 2, wherein the conductive layer further comprises a metal  
2 deposited onto the conductive polymer.

1 7. (currently amended) The method of claim 1, wherein the selected portions of the  
2 conductive layer on the top surface of the Ferroelectric ferroelectric material are selected  
3 by patterning the conductive layer on the top surface of the Ferroelectric ferroelectric  
4 material.

1 8. (currently amended) The method of claim 7, wherein the conductive layer on the top  
2 surface of the Ferroelectric ferroelectric material is patterned by:  
3 a. forming a mask over the conductive layer on the top surface of the Ferroelectric  
4 ferroelectric material;  
5 b. selectively removing the exposed portion of the conductive layer on the top  
6 surface of the Ferroelectric ferroelectric material; and  
7 c. removing the mask.

1 9. (original) The method of claim 8, wherein the mask is formed from a photo-resist.

1 10. (currently amended) The method of claim 9, wherein the mask is formed by:  
2 a. depositing the photo-resist on the conductive layer on the top surface of the  
3 Ferroelectric ferroelectric material;  
4 b. exposing areas of the photo-resist with a light source according to a predetermined  
5 pattern; and  
6 c. developing the photo-resist to remove the unexposed portions of the photo-resist.

1 11. (currently amended) The method of claim 1, further comprising the steps of placing the  
2 conductive layer on the top surface of the Ferroelectric ferroelectric material and the  
3 conductive layer on the bottom surface of the Ferroelectric ferroelectric material in  
4 electrical communication.

1 12. (currently amended) The method of claim 11, wherein the step of placing the conductive  
2 layer on the top surface of the Ferroelectric ferroelectric material and the conductive layer

FORM PTO-1449 (Modified)		JUL 14 2003 <b>U.S. Department of Commerce Patent and Trademark Office</b>		Attorney Docket No.: SLM-06100		Serial No.: 10/047,550	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)				Applicants: Gregory D. Miller et al			
(37 CFR § 1.98(b))				Filing Date: January 15, 2002		Group Art Unit: 2881 1731	

  

U.S. PATENT DOCUMENTS							
Examiner Initials		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date
CF	AA	Des. 334,557	04/06/93	Hunter et al.	D14	114	10/23/90
CF	AB	Des. 334,742	04/13/93	Hunter et al.	D14	113	10/03/90
CF	AC	Des. 337,320	07/13/93	Hunter et al.	D14	113	10/03/90
CF	AD	Re. 16,767	10/11/27	Jenkins	—	—	10/31/22
CF	AE	Re. 25,169	05/15/62	Glenn	—	—	06/01/54
	AF						
	AG						
	AH						
	AI						

  

FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS								
		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
CF	AI	DE 32 33 195 A1	03/17/83	DE	H 01 L	23/52		X
CF	AK	DE 43 23 799 A1	01/20/94	DE	H 01 L	23/50		X
CF	AL	DE 197 23 618 A1	12/11/97	DE	G 03 F	1/14		X
CF	AM	DE 197 51 716 A1	05/28/98	DE	G 02 B	27/14		X
CF	AN	DE 198 46 532 C1	5/31/2000	DE	G 02 B	27/09		X
CF	AO	0 089 044 A2	09/21/83	EP	H 01 L	23/10		X
CF	AP	0 261 901 A2	03/30/88	EP	G09G	3/36		X
CF	AQ	0 304 263 A2	02/22/89	EP	H 01 L	25/065		X
CF	AR	0 306 308 A2	03/08/89	EP	H 04 N	3/14		X
CF	AS	0 314 437 A1	10/25/88	EP	H 01 L	25/08		X
CF	AT	0 322 714 A2	07/05/89	EP	G 02 B	5/30		X
CF	AU	0 417 039 A1	03/13/91	EP	G 03B	21/20	X	
CF	AV	0 423 513 A2	04/24/91	EP	H01S	3/085		X
CF	AW	0 436 738 A1	07/17/91	EP	H04N	5/74		X
CF	AX	0 458 316 A2	11/27/91	EP	G06K	11/06		X
CF	AY	0 477 566 A2	04/01/92	EP	G02B	26/08		X
CF	AZ	0 488 326 A3	06/03/92	EP	G09G	3/28		X
CF	BA	0 499 566 A2	08/19/92	EP	G06F	3/033		X
CF	BB	0 528 646 A1	02/24/93	EP	G09G	3/02		X

  

Examiner: <i>ca-fro</i>	Date Considered: 5/11/04
-------------------------	--------------------------

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449  
(Modified)

JUL 1 6 2003

U.S. Department of Commerce  
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

INFORMATION DISCLOSURE STATEMENT BY APPLICANT  
(Use Separate Sheets If Necessary)

Applicants: Gregory D. Miller et al

(37 CFR § 1.98(b))

Filing Date: January 15, 2002

Group Art Unit: 2881 1731

## FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
CE	BC	0 530 760 A2	03/10/93	EP	G09G	3/34		X
CE	BD	0 550 189 A1	07/07/93	EP	G02F	1/315		X
CE	BE	0 610 665 A1	08/17/94	EP	G09G	3/34		X
CE	BF	0 627 644 A2	12/07/94	EP	G02B	27/00		X
CE	BG	0 627 644 A3	09/11/90	EP	G02B	27/00		X
CE	BH	0 627 850 A1	12/07/94	EP	H04N	5/64		X
CE	BI	0 643 314 A2	03/15/95	EP	G02B	27/00		X
CE	BJ	0 654 777 A1	05/24/95	EP	G09G	3/34		X
CE	BK	0 658 868 A1	06/21/95	EP	G 09G	3/34		X
CE	BL	0 658 830 A1	12/06/95	EP	G09G	3/34		X
CE	BM	0 689 078 A1	12/27/95	EP	G02B	26/08		X
CE	BN	0 801 319 A1	10/15/97	EP	G02B	26/00		X
CE	BO	0 851 492 A2	07/01/98	EP	H01L	23/538		X
CE	BP	1 003 071 A2	05/24/00	EP	G03B	27/72		X
CE	BQ	1 014 143 A1	06/28/00	EP	G02B	26/08		X
CE	BR	1 040 927 A2	10/04/00	EP	B41J	2/455		X
CE	BS	GB 2 117 564 A	10/12/83	GB	H 01 L	25/08		X
CE	BT	GB 2 118 365 A	10/26/83	GB	H 01 L	27/13		X
CE	BU	GB 2 266 385 A	10/27/93	GB	G02B	23/10		X
CE	BV	GB 2 296 152 A	06/19/96	GB	H04N	13/04		X
CE	BW	GB 2 319 424 A	05/20/98	GB	H04N	13/04		X
CE	BX	JP 1-155637	06/19/89	JP	H01L	21/66		X
CE	BY	JP 4-333015	11/20/92	JP	G02B	27/18		X
CE	BZ	JP 2219092	08/31/90	JP	G09G	3/28		X
CE	CA	JP 3288369	03/15/02	JP	G 02 B	26/06		X
CE	CB	JP 53-39068	04/10/78	JP	H 01 L	23/12		X
CE	CC	JP 55-111151	08/27/80	JP	H 01 L	27/00		X
CE	CD	JP 57-210638	12/24/82	JP	H 01 L	21/60		X
CE	CE	JP 57-31166	02/19/82	JP	H 01 L	23/48		X
CE	CF	JP 60-49638	03/18/85	JP	H 01 L	21/60		X
CE	CG	JP 60-94756	05/27/85	JP	H 01 L	25/04		X
CE	CH	JP 60-250639	12/11/85	JP	H 01 L	21/58		X
CE	CI	JP 61-142750	06/30/86	JP	H 01 L	21/60		X
CE	CJ	JP 61-145838	07/03/86	JP	H 01 L	21/60		X
CE	CK	JP 63-234767	09/30/88	JP	H 04 N	1/04		X

Examiner:

Date Considered:

EXAMINER:

Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RECEIVED

JUL 1 8 2003

GROUP 1700

FORM PTO-1449  
(Modified)U.S. Department of Commerce  
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

INFORMATION DISCLOSURE STATEMENT BY APPLICANT  
(Use Several Sheets If Necessary)

Applicants: Gregory D. Miller et al

(37 CFR § 1.98(b))

Filing Date: January 15, 2002

Group Art Unit: 2801 1731

## FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS

		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
CE	CL	JP 63-305323	12/13/88	JP	G 02F	1/13		X
CE	CM	JP 40-1155637	06/19/89	JP	H 01 L	21/92		X
CE	CN	JP 7-281161	10/27/95	JP	G02F	1/1333		X
CE	CO	WO 90/13913	11/15/90	WO	H 01 L	23/10		X
CE	CP	WO 92/12506	07/23/92	WO	G09F	9/37		X
CE	CQ	WO 93/02269	02/04/93	WO	E 06B	5/10		X
CE	CR	WO 93/09472	05/13/93	WO	G 03F	7/20	X	
CE	CS	WO 93/18428	09/16/93	WO	G02B	2700		X
CE	CT	WO 93/22694	11/11/93	WO	G02B	5/18		X
CE	CU	WO 94/09473	04/28/94	WO	G09G	3/34		X
CE	CV	WO 94/29761	12/22/94	WO	G02B	27/24		X
CE	CW	WO 95/11473	04/27/95	WO	G02B	27/00	X	
CE	CX	WO 96/02941	02/01/96	WO	H 01 L	23/02		X
CE	CY	WO 96/08031	03/14/96	WO	H01J	29/12		X
CE	CZ	WO 96/41217	12/19/96	WO	G02B	5/18		X
CE	DA	WO 96/41224	12/19/96	WO	G02B	19/00		X
CE	DB	WO 97/22033	06/19/97	WO	G02B	27/22		X
CE	DC	WO 97/26569	07/24/97	WO	G02B	5/18		X
CE	DD	WO 98/05935	02/12/98	WO	G01L	9/06		X
CE	DE	WO 98/24240	06/04/98	WO	H04N	9/31		X
CE	DF	WO 98/41893	09/24/98	WO	G02B	26/08		X
CE	DG	WO 99/07146	02/11/99	WO	H04N	7/16		X
CE	DH	WO 99/12208	03/11/99	WO	H 01 L	25/065		X
CE	DI	WO 99/23520	05/14/99	WO	G 02 B	26/08		X
CE	DJ	WO 99/34484	07/08/99	WO	H01S			X
CE	DK	WO 99/59335	11/18/99	WO	H04N	5/165		X
CE	DL	WO 99/63388	12/09/99	WO	G02B	27/22		X
CE	DM	WO 99/67671	12/29/99	WO	G02B	26/08		X
CE	DN	WO 00/04718	01/27/00	WO	H04N	7/167		X
CE	DO	WO 00/07225	02/10/00	WO	H01L	21/00		X
CE	DP	WO 01/04674 A1	01/18/01	WO	G02B	6/12		X
CE	DQ	WO 01/006297 A3	01/25/01	WO	G02B	27/10		X
CE	DR	WO 01/57581 A3	08/09/01	WO	G02B	27/48		X

Examiner:

Date Considered: 5/11/04

EXAMINER:

Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 (Modified)		JUL 1 4 2003		U.S. Department of Commerce Patent and Trademark Office		Attorney Docket No.: SLM-06100		Serial No.: 10/047,550	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)						Applicants: Gregory D. Miller et al			
(37 CFR § 1.98(b))						Filing Date: January 15, 2002		Group Art Unit: <del>3884</del> 1731	
FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS									
		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation		
							Yes	No	
CF	DS	WO 02/025348 A3	03/28/02	WO	G02B	26/02		X	
CF	DT	WO 02/31575 A2	04/18/02	WO	G02B	27/00		X	
CF	DU	WO 02/058111 A2	07/25/02	WO	H01L				
CF	DV	WO 02/065184 A3	08/22/02	WO	G02B	27/12			
CF	DW	WO 02/073286 A2	09/19/02	WO	G02B	26/08			
CF	DX	WO 02/084375 A1	10/24/02	WO	G02B	26/08			
CF	DY	WO 02/084397 A3	10/24/02	WO	G02B	27/18			
CF	DZ	WO 03/001281 A1	01/03/03	WO	G02F	1/01		X	
CF	EA	WO 03/001716 A1	01/03/03	WO	H04J	14/02		X	
CF	EB	WO 03/012523 A1	02/13/03	WO	G02B	26/00		X	
CF	EC	WO 03/016965 A1	02/27/03	WO	G02B	5/18		X	
CF	ED	WO 03/023849 A1	03/20/03	WO	H01L	23/02		X	
CF	EE	WO 03/025628 A2	03/27/03	WO	G02B			X	
OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)									
CF	EF	R. Apte, "Grating Light Valves for High Resolution Displays", Solid State Sensors and Actuators Workshop, Ph D. Dissertation, Stanford University (June 1994).							
CF	EG	O. Solgaard, "Integrated Semiconductor Light Modulators for Fiber-Optic and Display Applications", Ph.D. Dissertation, Stanford University February, 1992.							
CF	EH	J. Neff, "Two-Dimensional Spatial Light Modulators: A Tutorial", Proceedings of the IEEE, vol. 78, No. 5 (May 1990), pp. 826-855.							
CF	EI	R. Gerhard-Multhaupt, "Viscoelastic Spatial Light Modulators and Schlieren-Optical Systems for HDTV Projection Displays" SPIE vol. 1255 Large Screen Projection Displays II (1990), pp. 69-78.							
CF	EJ	R. Gerhard-Multhaupt, "Light-Valve Technologies for High-Definition Television Projection Displays", Displays vol. 12, No. 3/4 (1991), pp. 115-128.							
CF	EK	O. Solgaard, F. Sandejas, and D. Bloom, "Deformable Grating Optical Modulator," Optics Letters, Vol. 17, No. 9, May 1, 1992, New York, USA, pp. 688-690.							
CF	EL	F. Sandejas, R. Apte, W. Banyai, and D. Bloom, "Surface Microfabrication of Deformable Grating Valve for High Resolution Displays," The 4th International Conference on Solid-State Sensors and Actuators.							
CF	EM	P. Alvela, "High-Efficiency Color Microdisplays," SID 95 Digest, pages 307-311, 1995.							
CF	EN	Worboys et al., "Miniature Display Technology for Integrated Helmut Systems," GEC Journal of Research, Vol. 10, No. 2, pages 111-118, Chelmsford, Essex, GB 1993.							
CF	EO	M. Farn et al., "Color Separation by use of Binary Optics," Optics Letters, Vol. 18:15 pages 1214-1216, 1993.							
CF	EP	P. Alvela, "VLSI Microdisplays and Optoelectric Technology," MIT, pages 1-93, 1995.							
CF	EQ	P. Alvela, "VLSI Microdisplay Technology," October 14, 1994.							
Examiner:		<i>caz</i>				Date Considered: 5/11/04			
EXAMINER:		Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

FORM PTO-1449 (Modified)		JUL 14 2003 U.S. Department of Commerce Patent and Trademark Office		Attorney Docket No.: SLM-06100		Serial No.: 10/041450	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)				Applicants: Gregory D. Miller et al		Filing Date: January 15, 2002	
(37 CFR § 1.98(b))				Group Art Unit: 2601		173	
OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)							
CF	ER	D. Rowe, "Laser Beam Scanning," SPIE, Vol. 2088, Oct. 5, 1993, 18-26					
CF	ES	L. Hornbeck, "Deformable-Mirror Spatial Light Modulators," Spatial Light Modulators and Applications III, Aug. 8, CA 1989, pp. 86-102					
CF	ET	Russick et al., "Supercritical Carbon Dioxide Extraction of Solvent from Micromachined Structures," Supercritical Fluids, Chapter 18, American Chemical Society, pp 255-269, 1997.					
CF	EU	Buhler et al., "Linear Array of Complementary Metal Oxide Semiconductor Double-Pass Metal Micromirrors," Optical Engineering, Vol. 36, No. 5, pp 1391-1398, May 1997.					
CF	EV	Gani et al., "Variable Gratings for Optical Switching: Rigorous Electromagnetic Simulation and Design," Optical Engineering, Vol. 38, No. 3, pp 552-557, March 1999.					
CF	EW	R. Tepe, et al. "Viscoelastic Spatial Light Modulator with Active Matrix Addressing," Applied Optics, Vol. 28, No. 22, New York, USA, pp.4826-4834, Nov. 15, 1989.					
CF	EX	W. Brinker, et al., "Deformation Behavior of Thin Viscoelastic Layers Used in an Active-Matrix-Addressed Spatial Light Modulator," SPIE Vol. 1018, pp. 79-85, Germany, 1988.					
CF	EY	T. Utsunomiya and H. Sato, "Electrically Deformable Echelle Grating and its Application to Tunable Laser Resonator," Electronics and Communications in Japan, Vol. 63-c, No. 10, pp. 94-100, Japan, 1980.					
CF	EZ	Burns, D.M. et al., "Development of microelectromechanical variable blaze gratings," Sensors and Actuators A, pp. 7-15, 1998.					
CF	FA	R.N. Thomas, et al., "The Mirror-Matrix Tube: A Novel Light Valve for Projection Displays," IEEE Transactions on Electron Devices, Vol. ED-22, No. 9, pp. 765-775, September 1975.					
CF	FB	J. Guldberg, et al., "An Aluminum/SiO <sub>2</sub> /Silicon-on-Sapphire Light Valve Matrix for Projection Displays," Applied Physics Letters, Vol. 26, No. 7, pp. 391-393, April 1975.					
CF	FC	"Kitchen Computer," IBM Technical Disclosure Bulletin, vol. 37, no. 12, pp. 223-225, December 1994.					
CF	FD	"Image Orientation Sensing and Correction for Notepads", Research Disclosure, no. 34788, p. 217, March 1993.					
CF	FE	Beck Mason et al., "Directly Modulated Sampled Grating DBR Lasers for Long-Haul WDM Communication Systems" IEEE Photonics Technology Letters, Vol. 9, No. 3, March 1997, pp. 377 of 379.					
CF	FF	N. J. Frigo et al., "A Wavelength-Division Multiplexed Passive Optical Network with Cost-Shared Components", IEEE Photonics Technology Letters, Vol. 6, No. 11, November 1994, pp. 1365 of 1367.					
CF	FG	M. S. Goodman et al., "The LAMBDANET Multiwavelength Network: Architecture, Applications, and Demonstrations", IEEE Journal on Selected Areas in Communications, Vol. 8, No. 6, August 1990, pp. 995 of 1004.					
CF	FH	C. A. Turkotte, "Examining the Benefits of Tunable Lasers for Provisioning Bandwidth on Demand", EuroForum - Optical Components, February 2001, pp. 1 of 10.					
CF	FI	R. Plastow, "Tunable Lasers and Future Optical Networks", Forum - Tunable Laser, August 2000, pp. 58 of 62.					
CF	FJ	Elizabeth Bruce, "Tunable Lasers", Communications, IEEE Spectrum, February 2002, pp. 35 of 39.					
CF	FK	M. G. Littman et al., "Spectrally Narrow Pulsed Dye Laser without Beam Expander", Applied Optics, Vol. 17, No. 14, July 15, 1978, pp. 2224 of 2227.					
CF	FL	Apte et al., "Deformable Grating Light Valves for High Resolution Displays," Solid State Actuator Workshop, Hilton Head, South Carolina, June 13-16, 1994.					
CF	FM	Sene et al., "Polysilicon micromechanical gratings for optical modulation," Sensors and Actuators, Vol. A57, pp. 145-151, 1996.					
CF	FN	Arrn et al., "Invited Paper: Grating Light Valve™ Technology: Update and Novel Applications," SID Digest, Vol. 29, 1998.					
CF	FO	Development of Digital MEMS-Based Display Technology Promises Improved Resolution, Contrast, and Speed", XP-000730009, 1997, pp. 33 of 34.					
CF	FP	"Micromachined Opto/Electro/Mechanical Systems," Electronic Systems, NASA Tech Briefs, March 1997, pgs. 50 & 52.					
CF	FQ	S.T. Pai, et al., "Electromigration in Metals", Received June 4, 1976, pg. 103-115.					
CF	FR	Olga B. Spahn, et al., "High Optical Power Handling of Pop-Up Microelectromechanical Mirrors", Sandia National Laboratories, IEEE 2000, pg. 51-52.					
CF	FS	David M. Burns, et al. "Optical Power Induced Damage to Microelectromechanical Mirrors", Sensors and Actuators A 70, 1998, pg. 6-14.					
CF	FT	V.S. Aliev et al., "Development of Si(100) surface roughness at the initial stage of etching in F2 and XeF2 gases: ellipsometric study," Surface Science 442 (1999), pgs. 206-214.					
CF	FU	Xuan-Qi Wang et al., "Gas-Phase Silicon Etching with Bromine Trifluoride," Depart. of Electrical Engineering, 136-93 California Institute of Technology, 1997 IEEE, pgs. 1505-1508.					
Examiner:		Date Considered:			5/1/04		
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

RECEIVED  
JUL 18 2003  
GROUP 1700



FORM PTO-1449 (Modified) Office		U.S. Department Patent and Trademark		Attorney Docket No.: SLM-06100	Serial No.: 10/047,550
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)				Applicants: Gregory D. Miller et al	
(37 CFR § 1.98(b))				Filing Date: January 15, 2002	Group Art Unit: 2881 173
OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)					
CF	FV	Harold F. Winters, "Etch products from the reaction of XeF <sub>2</sub> with SiO <sub>2</sub> , Si <sub>3</sub> N <sub>4</sub> , SiC, and Si in the presence of Ion Bombardment," IBM Research Laboratory, 1983 American Vacuum Society, pgs. 927-931.			
CF	FW	F.A. Houle, "Dynamics of SiF <sub>4</sub> desorption during etching of silicon by XeF <sub>2</sub> ," J. Chem. Phys. 87 (3), 1 August 1987, pgs. 1866-1872.			
CF	FX	Mehran Mehregany, "Microelectromechanical Systems," 1993 IEEE, pgs. 14-22.			
CF	FY	D. Moser et al., "A CMOS Compatible Thermally Excited Silicon Oxide Beam Resonator with Aluminium Mirror," Physical Electronics Laboratory, 1991 IEEE, pgs. 547-550.			
CF	FZ	M. Parameswaran et al., "Commercial CMOS Fabricated Integrated Dynamic Thermal Scene Simulator," 1991 IEEE, pgs. 29.4.1-29.4.4.			
CF	GA	M. Parameswaran et al., "CMOS Electrothermal Microactuators," Depart. of Electrical Engineering, 1990 IEEE, pgs. 128-131.			
CF	GB	U. Streller et al., "Selectivity in dry etching of Si(100) with XeF <sub>2</sub> and VUV light," Applied Surface Science 106, (1996), pgs. 341-346.			
CF	GC	M.J.M. Vugts et al., "Si/XeF <sub>2</sub> etching: Temperature dependence," 1996 American Vacuum Society, pgs. 2766-2774.			
CF	GD	P. Krummenacher et al., "Smart Temperature Sensor in CMOS Technology," Sensors and Actuators, A-21-A-23 (1990), pgs. 636-638.			
CF	GE	Henry Baltes, "CMOS as sensor technology," Sensors and Actuators A. 37-38, (1993), pgs. 51-56.			
CF	GF	Thomas Boltshauser et al., "Piezoresistive Membrane Hygrometers Based on IC Technology," Sensor and Materials, 5, 3, (1993), pgs. 125-134.			
CF	GG	Z. Parpia et al., "Modelling of CMOS Compatible High Voltage Device Structures," pgs. 41-50.			
CF	GH	Jon Gildemeister, "Xenon Difluoride Etching System," 1997, UC Berkeley MicroFabrication Manual Chapter 7.15, pg. 2-5.			
CF	GI	W. Riethmuller et al., "A smart accelerometer with on-chip electronics fabricated by a commercial CMOS process," Sensors and Actuators A. 31, (1992), 121-124.			
CF	GJ	W. Gopel et al., "Sensors- A Comprehensive Survey," Vol. 7, Weinheim New York, 44 pgs.			
CF	GK	D. E. Ibbotson et al., "Comparison of XeF <sub>2</sub> and F-atom reactions with Si and SiO <sub>2</sub> ," 1984 American Institute of Physics, pgs. 1129-1131.			
CF	GL	D. E. Ibbotson et al., "Plasmaless dry etching of silicon with fluorine-containing compounds," 1984 American Institute of Physics, pgs. 2939-2942.			
CF	GM	M.H. Hecht et al., "A novel x-ray photoelectron spectroscopy study of the Al/SiO <sub>2</sub> interfaces," 1985 American Institute of Physics, pgs. 5256-5261.			
CF	GN	Daniel L. Flamm et al., "XeF <sub>2</sub> and F-Atom Reactions with Si: Their Significance for Plasma Etching," Solid State Technology, V. 26, #4, 4/83, pgs. 117-121.			
CF	GO	H.F. Winters et al., "The etching of silicon with XeF <sub>2</sub> vapor," Appl. Phys. Lett. Vol. 34, No. 1, January 1979, pgs. 70-73.			
CF	GP	Wayne Bailey et al., "Microelectronic Structures and Microelectromechanical Devices for Optical Processing and Multimedia Applications," SPIE - The International Society for Optical Engineering, Vol. 2641, October 1995, 13 pgs.			
CF	GQ	J. Marshall et al., "Realizing Suspended Structures on Chips Fabricated by CMOS Foundry Processes Through the MOSIS Service," National Inst. of Standards and Technology, Jun 94, 63 pgs.			
CF	GR	David Moser et al., "CMOS Flow Sensors," 1993 Physical Electronics Lab, Swiss Federal Institute of Tech, Zurich, Switzerland, 195 pgs.			
CF	GS	E. Hecht, "Optics", Addison-Wesley, 2 <sup>nd</sup> edition, 1987, Adelphi University, pp. 163-169.			
CF	GT	E. Hecht, "Optics", Addison-Wesley, 2 <sup>nd</sup> edition, 1987, Adelphi University, pp. 358-360.			
CF	QU	T. Glaser et al., "Beam switching with binary single-order diffractive grating", XP-000802142, Optics Letters, December 15, 1998, Vol. 23, No. 24, pp. 1933 of 1935.			
CF	GV	P. C. Kundu et al., "Reduction of Speckle Noise by Varying the Polarisation of Illuminating Beam", XP-002183475, Dept. of Applied Physics, Calcutta University, 1975, pp. 63-67.			
CF	GW	J. W. Goodman, "Some Fundamental Properties of Speckle", XP-002181682, Dept. of Electrical Engineering, Stanford University, 1976, pp. 1146-1150.			
CF	GX	Lingli Wang et al., "Speckle Reduction in Laser Projection Systems by Diffractive Optical Elements", XP-000754330, Applied Optics, April 1, 1998, Vol. 37, No. 10, pp. 1770-1775.			
Examiner:		Date Considered: 5/11/04			
EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					

RECEIVED  
JUL 18 2003  
GROUP 1700



FORM PTO-1449  
(Modified)

U.S. Department of Commerce  
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

INFORMATION DISCLOSURE STATEMENT BY APPLICANT  
(Use Several Sheets If Necessary)

Applicants: Gregory D. Miller et al

Filing Date: January 15, 2002

Group Art Unit: 2881 1731

(37 CFR § 1.98(b))

OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

CF	GY	R.W. Corrigan et al., "Calibration of a Scanned Linear Grating Light-Valve, Projection System for E-Cinema Applications", Silicon Light Machines, SID'99, San Jose, CA, 27 pgs, 1999.
CF	GZ	R.W. Corrigan et al., "Calibration of a Scanned Linear Grating Light-Valve, Projection System", Silicon Light Machines, San Jose, CA, 4 pgs, May 18, 1999.
CF	HA	"Introduction to Cryptography", <a href="http://www.ssh.fi/tech/crpto/into.html">http://www.ssh.fi/tech/crpto/into.html</a> , 35 pgs, June 21, 1999.
CF	HB	"Deep Sky Black," Equinox Interscience, <a href="http://www.eisci.com/deepsky.html">www.eisci.com/deepsky.html</a> , 1997.
CF	HC	"Absorptive Neutral Density Filters," Newport Corp., Irvine, CA, <a href="http://www.newport.com">www.newport.com</a> , 5/7/99.
CF	HD	"High Energy Variable Attenuators," Newport Corp., Irvine, CA, <a href="http://www.newport.com">www.newport.com</a> , 5/7/99.
CF	HE	"Neutral-Density Filters," New Focus, Inc., Santa Clara, CA, <a href="http://www.newfocus.com">www.newfocus.com</a> , 5/7/99.
CF	HF	J. Hawkes et al., "Laser Theory and Practice," Prentice Hall, New York, 1995, pp. 407-408.
CF	HG	C. Tew et al., "Electronic Control of a Digital Micromirror Device for Projection Displays", Proceedings of the 1994 IEEE International Solid-State Circuits Conference, 1994.
CF	HH	Henck, S.A., "Lubrication of Digital Micromirror Devices", Tribology Letters, No. 3, pp. 239-247, 1997.
CF	HI	K. W. Goossen et al., "Silicon Modulator Based on Mechanically-Active Anti-Reflection Layer with 1 Mbit/sec Capability for Fiber-in-the-Loop Applications", IEEE Photonics Technology Letters, Vol. 6, No. 9, September 1994, pp. 1119-1121.
CF	HJ	J.A. Walker et al., "Demonstration of a Gain Flattened Optical Amplifier with Micromechanical Equalizer Element", Lucent Technologies, pp. 13-14.
CF	HK	A. P. Payne et al., "Resonance Measurements of Stresses in Al/SiN <sub>x</sub> Micro-Ribbons", Silicon Light Machines, September 22, 1999, 11 pgs.
CF	HL	M. W. Miles, "A New Reflective FPD Technology Using Interferometric Modulation", 4 pgs.
CF	HM	N. A. Riza et al., "Digitally Controlled Fault-Tolerant Multiwavelength Programmable Fiber-Optic Attenuator Using a Two-Dimensional Digital Micromirror Device", OPTICS LETTERS, March 1, 1999, Vol. 24, No. 5, pp. 282-284.
CF	HN	N. A. Riza et al., "Synchronous Amplitude and Time Control for an Optimum Dynamic Range Variable Photonic Delay Line", APPLIED OPTICS, April 10, 1999, Vol. 38, No. 11, pp. 2309-2318.
CF	HO	P. Alvela et al., "44.4: Ferroelectric Microdisplays Using Distortion-Compensated Pixel Layouts", SID 95 DIGEST, XP 2020715, pp. 931-933.
	HP	
	HQ	
	HR	
	HS	
	HT	
	HU	
	HV	
	HW	
	HX	
	HY	
	HZ	
	IA	
	IB	

Examiner:

CA-700

Date Considered:

5/11/04

EXAMINER:

Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RECEIVED  
JUL 18 2008  
GROUP 1700